IN THE CLAIMS:

Please amend claims 1 and 3-5 as follows:

1	1. (Currently Amended) A method of manufacturing a head slider,
2	comprising the steps of:
3	forming a magnetizable layer on a surface of a substrate wafer having a
4	thickness greater than a length of the slider;
5	cutting said wafer into a plurality of raw bars after forming said layer while
6	said thickness of said wafer is still greater than said length of the slider;
.7	supporting said plurality of raw bars by a supporting jig;
8	arranging dummy sections of said plurality of raw bars in a single direction;
9	forming air bearing surface patterns on air bearing surface faces of said
10	plurality of raw bars by photolithography; and
11	removing said dummy sections from [[the]] said plurality of raw bars after
12	forming said air bearing surface patterns.
1	2. (Previously Presented) The method according to claim 1, wherein
2	said plurality of raw bars have thicknesses greater than a length of said slider, and are
3	supported by said supporting jig in a machining step.

1 3. (Currently Amended) The method according to claim 1, wherein said dummy sections of [[a]] said plurality of raw bars are arranged on one side in said 2 3 supporting jig. 4. (Currently Amended) The method according to claim 1, further 1 comprising the step of [[:]] cutting at least one of said plurality of raw [[bar]] bars so as to 2 form the slider. 3 5. (Currently Amended) The method according to claim 1, further 1 2 comprising the step of[[:]] removing the dummy section sections before cutting into at least 3 one of said plurality of raw [[bar]] bars. 1 6. (Withdrawn) A method of manufacturing a magnetic head, comprising 2 the steps of: 3 forming a plurality of layers including a magnetizable layer on a surface of a 4 substrate; 5 cutting said substrate so as to form a plurality of raw bars; and 6 removing a prescribed part of each raw bar, from one end face, in a direction of

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piling said layers.